trivalent inpurities -> boson, gallium, in dium, aluminum.

Pentavalent inpusities: Assenic, phosphosous, Antimony

- -> the graient of charge concentration, in p47 type material help to diffuse the hole and electron.
  - > there is built in potential in the diode from n to p due to the
  - > under Equilibrium diffusion current setup electric field which lead to the drift current in apposite direction.

Electron diffusc

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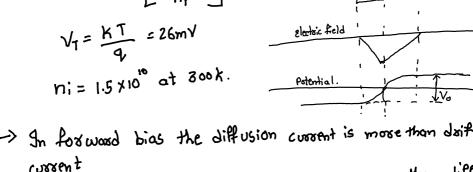
Pletron drift (minority coursits)

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- -> the p-side is doped more than the n side the charge density in P Side is more than the ntype.
- -> the built in potential is given by formula

$$V_0 = V_T \int_{\Omega} \frac{N_A N_D}{n_i^2}$$



- -> In forward bias the diffusion current is more than drift cussent
- current is more than diffusion - In reverse bias the drift current. there are less minority corrier for driff current in reverse bas.

-> the diode Equation is given by the formula

-> the diode Equation is given by the formula
$$I_D = I_S \left( e^{\frac{1}{N_T}} - 1 \right)$$

-> Is depends on \\_\_\_ > doping concentration.

-> Electric field(Ei) =  $\sqrt{\frac{29}{E_{Si}}} \frac{N_A N_D}{N_A + N_D} (N_0 - N_D)$ 

 $\frac{1}{2} \frac{1}{2} = \frac{NA}{NO} \qquad \frac{1}{2} \Rightarrow \text{width of n type}$   $\frac{1}{2} \frac{1}{2} \frac{1}{2}$ 

 $\Rightarrow$  Junction capacitance (Cj)  $\Rightarrow$   $A_D \sqrt{\epsilon_{s,q}} \left( \frac{N_A N_D}{N_A + N_D} \right) \left( V_O - V_O \right)^{-1}$ 

from P to N material is instantanously

> Cj = Cjo (jo -> capacitance under zero bias /2 -> absupt diode .> m -> grading constant m = (1/3 -> linear or graded diode.

-> Equation G' is valid for about diode. Where transition

-> Depletion region width. Wz-W1-> ) 2 Esi Na+No (Vo-Vo)

Vo -> Voltage across

depletion layer.

-> Depletion region charge (Q) -> AD \( \frac{2 \end{args} \frac{N\_A ND}{N\_A + ND} \) (Vo-VD) of di

Cjo = AD J & Q NAND VO-1

A D -> Area of diode.

→ &si = 11.5 x 80

\* first order model of diode

ID= IS ( PNY -1)

Large Signal depletion - region capacitance

-> junction capacitance is Noltage dependent

> In digital circult voltage is moved sapidly wide sange under this ciscomstance it is attractive to replace voltage dependent

non-linear G with linear capacitance Ceq

Tempsoduse dependence of Jiode.

-> the break down voltage increase with. tempsatuse

-> the reverse saturation current double

the stresse satisfaction in temperature for every loc increase in temperature 
$$I_s(J_1) = I_1(J_1) \times 2^{(J_1 - I_2)} I_0$$

-> but in Voltage (VT) decorase with Increase in temprature.

\* diode capacitance.

Transition capacitance Cr

->during forward bias width decrease f CT increase 4 converse is true for reverse

biased.

-> Diffusion capacitance is Predominant in forward bias.

-> Co = day -> the change in the number of minority carrier with change -> it is in the voltage.

-> it is in the sange of 10-204 F in forward bias

> It effect the switching time of the diode the switching time constant of the diode equal to SaxCo. where &d is dynamic forward resistance

- -> consider Vas=0 + Vs=0 Vp=0 VB=0. It can be madelled as connection of two diode back to back these act as & etsernely high resistance between
- -> the positive voltage is applied to gate with respective Body. this act as
- > the positive charge on the gate repell the holes in the body which coreate NA-> substrate doping the depletion region.
- $\Rightarrow$  the width of depletion region  $U_d = \sqrt{\frac{2 \text{ Es; Vo}}{9, N_A}}$ No > Voltage of depletion region. -> the charge on depletion layer Qd= \square 2q,NA Esi Vo
- -> As the gate voltage is increase, the potential on the silicon surface seach.

  Coitial Value . It is invested to n type material this is called strong investion. it accours at a voltage Equal to twice the fermi potential.

$$V_F = -V_T 4n \left( \frac{N_A}{n_i} \right)$$

- > forther increase in Voltage doesn't increase the depletion reagion but it increase the current in depletion region.
- -> In strong inversion the charge stored is given by formula.

- -> The value of Vgs where strong inversion occur is called VT
- -> VT is is function of

L> difference in work function between gate 4 substrate L> oxide thickness, Inpurities trapped between channel 4 gate

V<sub>T</sub> = 
$$V_{To} + \delta \left( \sqrt{|-zV_F + V_{SB}|} - \sqrt{|-2V_F|} \right)$$

$$V_T = V_{To} + \delta \left( \sqrt{|-zV_F + V_{SB}|} - \sqrt{|-2V_F|} \right)$$

VTO => VT fox VSB=0

8 >> Body Effect co-Efficient.